

197310US2 PCT



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

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TC 1700

IN RE APPLICATION OF: :  
Sumi TANAKA, et al. : EXAMINER: MOORE, K.  
SERIAL NO.: 09/646,343 :  
RCE FILED: Herewith : GROUP ART UNIT: 1763  
FOR: FILM FORMING DEVICE :

# 9  
1/28/03  
MW

AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

In response to the Official Action dated September 20, 2002, please amend the above-identified application as follows:

IN THE CLAIMS

Claims 1 and 2 are amended as follows:

- C1
1. (Twice Amended) A film deposition apparatus comprising:
- a container forming a processing chamber for processing a target object;
  - a mounting table which is provided in the processing chamber and on which the target object is mounted;
  - a first heating apparatus provided in the mounting table;
  - a first gas supply <sup>section</sup> provided in the container, for supplying processing gas into the processing chamber, the processing gas forming a thin film on the target object mounted on the mounting table;